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Electrodeposition of copper applied to the manufacture of seamless SRF cavities

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Outline

1. Current production process/problematic

2.Technical proposal

3.Samples characterization

4. Dislocation density by EBSD

5.Towards first 1.3 GHz cavity

6.Optimization of the process

Production of copper SRF substrates

STANDARD METHOD - Half cell spinning and welding



Half cell spinning

Welding

Possible defects





Weld porosities

- Presence of porosities along the junction caused by the welding process
- Copper sheets can contain defects

Production of copper SRF substrates

SEAMLESS METHOD - Cell spinning around mandrel



Cell spinning

Cut-offs welding

Additional possible defects

– – – Beam axis



Mandrel footprint Cu cracking

- Mandrel footprint can appear on the copper surface
- Large deformation introduced in the process can lead to high cracking

Cu electroforming - approach

The cavity is produced by copper electroforming around a sacrificial aluminium mandrel which is precoated with a copper thin film.



- Robust and leak-tight seamless cavity
- Challenges
- Smooth inner surface state
- High copper purity and conductivity

Cu electroforming - approach

• Study the properties of electroformed copper in flat samples



• Study the robustness of the assembly in prepared cavity test dummies



DC plating



Pulsed plating (PP)

Dummy2

Electroformed copper properties

• UTS/ Young modulus



Roughness



Electroformed copper properties

Residual Resistivity Ratio





- DC matches Cu OFE specs after thermal treatment
- PP can lead to very high RRR without thermal treatment

- Thermal conductivity
- Samples measured after deposition
- Pulse plated sample conductivity 5 times larger than OFE spec.



- After 2h at 400°C
- Triplicated conductivity for DC plated after thermal treatment

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Electron back scatter diffraction (EBSD)

Cu OFE by Spinning and Electro-Hydraulic Forming (EHF)





Iris samples



E. García-Tabarés et al, Electron Backscatter Diffraction meeting. Plymouth, April 2018.

- To accommodate plastic deformation, the material generates dislocations, which disturb the structure of the lattice and lead to local misorientations.
- Study local misorentation by measuring the kernel average misorientation (KAM).
- This criteria displays small orientation gradients, highlighting areas of high Geometrically Necessary Dislocations (GND) density.



EBSD and dislocation density

<KAM>

7

6

5.5

5

4 3.5 3 2.5 2 1.5 1 0.5 0

4.5

6.5



Dummy2 **Pulse plated cavity**





Equator samples



Horizontal plane $200\,\mu m$



EBSD and dislocation density



Spinning vs Electro-Hydraulic Forming

- Low dislocation density in electroformed copper.
- Similar GND density than reference copper OFE before machining.





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1.3 GHz Mandrel production

How to produce such an aluminium mandrel?

Machined from bulk aluminium



Mandrel cell turning

Mechanical finishing

Tubes welding/machining

For the moment: Standard machining finishing











Cathode (reduction): Cu²⁺ + 2e⁻ → Cu

Anode (oxidation): $Cu \rightarrow Cu^{2+} + 2^{e-}$



336 hours of plating (Pulse plating + DC plating)



- 2 mm plating at the iris
- 6.4 mm plating at the equator





Aluminum dissolution NaOH 5M

Surface preparation: SUBU





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Electroforming process

COMSOL simulations for optimization



Design of secondary anodes and masking

• Solution for uniformity: Secondary anodes positioned at the iris to promote plating, mask at the equator to reduce the deposition.



Design of secondary anodes and masking



Implementation of support





Fabrication









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Copper PVD process

Optimization of Cu coating process

- **HiPIMS sputtering:** high peak power densities in short pulses.
- The sputtered material is highly ionized and is accelerated towards substrate thanks to the positive pulse.
- High-quality dense homogeneous films

DCMS



High Power Impulse Magnetron Sputtering



HiPIMS + PP



- Very compact coatings.
- No porosities.

Conclusions



• Cavity lifecycle (production-coating-rinsing-testing-stripping) feasibility has been demonstrated with the electroformed 1.3 GHz cavity.



The main drawback of the electroforming approach is the non-uniform thickness distribution along the cavity.

Solution: secondary anodes and masking to the cavity. The plating time will be reduced by half.



- The Cu PVD layer was optimized by applying HiPIMS.
- Very low dislocation density on the iris and equator of electroformed cavity.

Perspectives

- 1.3 GHz cavity production and validation of the secondary anodes support.
- Optimal surface preparation technique before coating.
- Nb thin film coating using best recipe and RF testing.

- Different mandrels surface state: electroforming on polished mandrels.
 - Diamond turning finishing
 - Electro-polishing of the aluminium mandrels

Thank you for your attention!